

## Electronic Supplementary Information for

# Physical Vapor Deposition of Amorphous MoS<sub>2</sub> Nanosheet Arrays on Carbon Cloth towards Highly Reproducible Large-Area Electrocatalysts for Hydrogen Evolution Reaction

Xing Zhang, Yun Zhang, Bin-Bin Yu, Xing-Liang Yin, Wen-Jie Jiang, Yan Jiang, Jin-Song Hu\*, Li-Jun Wan\*

Beijing National Laboratory for Molecular Sciences, Key Laboratory of Molecular Nanostructure and Nanotechnology, Institute of Chemistry, Chinese Academy of Sciences (CAS), 2 North 1<sup>st</sup> Street, Zhongguancun, Beijing 100190, P.R. China. Fax: (+86) 10-82613929  
E-mail: hujs@iccas.ac.cn, wanlijun@iccas.ac.cn

## Experimental Section

### Synthesis of a-MoS<sub>2</sub> NA/CC

Carbon cloth (CC, Wuhan Instrument, Wuhan) was carefully cleaned with concentrated HNO<sub>3</sub> to remove impurities on surface, then rinsed by deionized water and ethanol before use. The deposition of a-MoS<sub>2</sub> was carried out on a magnetron sputtering system (PVD 75, Kurt J. Lesker, USA) using molybdenum sulfide (99.99%, Purui, Beijing) as the target. The deposition time was kept at 1000 s. The sputtering power was adjusted from 70 W to 150 W to control the morphology of the deposited a-MoS<sub>2</sub>. In order to keep the same loadings of MoS<sub>2</sub> for all the samples deposited at different power, we first measured the thickness of the MoS<sub>2</sub> thin film deposited on Si substrate in parallel with the samples to calculate the sputtering rate at different power. Then, we calibrated the sputtering time to obtain MoS<sub>2</sub> nanostructures on carbon cloth with the same loading of MoS<sub>2</sub> on carbon cloth by weighing the sample before and after the sputtering process.

### Electrochemical measurements

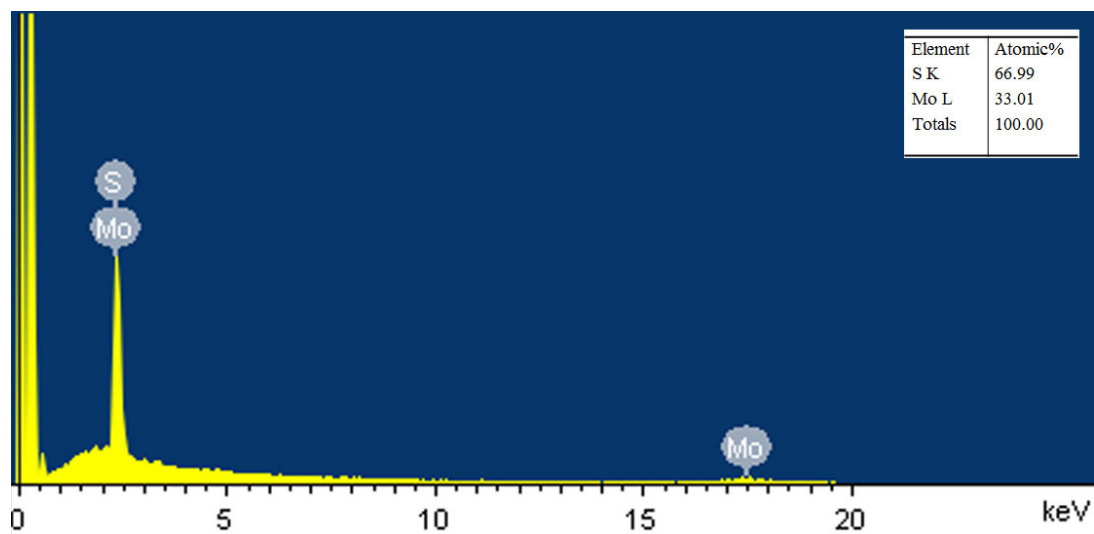
All electrochemical measurements were performed on a 760E bipotentiostat (CHI instruments) in a typical three electrode setup. In a typical measurement, a-MoS<sub>2</sub> NA/CC (0.5 × 0.5 cm) with a MoS<sub>2</sub> loading of ~0.41 mg cm<sup>-2</sup>

was used as a working electrode, a graphite rod as the counter electrode, and a saturated calomel electrode (SCE) as the reference electrode. The electrolyte solution is 0.5 M H<sub>2</sub>SO<sub>4</sub>. Another two a-MoS<sub>2</sub> nanostructured thin films obtained at different sputtering power with same loading (~0.41 mg cm<sup>-2</sup>) and commercial Pt/C catalyst (20 wt.% Pt, Johnson Matthey, 0.35 mg cm<sup>-2</sup>.) were also measured for comparison. In all measurements, the SCE reference electrode was calibrated with respect to reversible hydrogen electrode (RHE). LSV measurements were conducted at a scan rate of 2 mV/s. All the potentials reported in our work were versus RHE.

## **Characterizations**

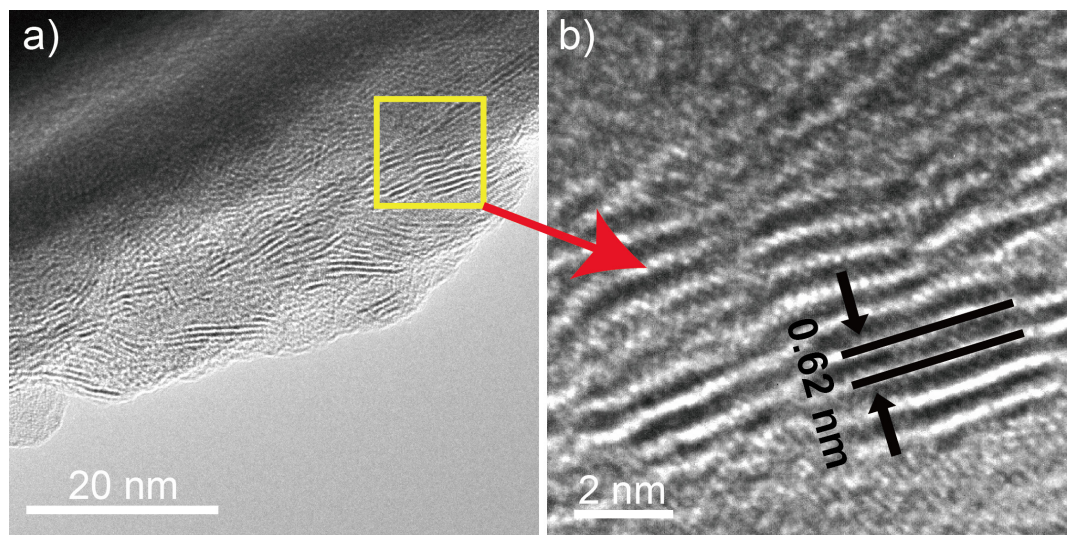
Morphology analysis was conducted using a Hitachi S-4800 field emission scanning electron microscope operated at 10 kV. Elemental mapping and electron energy dispersive spectroscopy (EDS) were performed with a EDS detector equipped on the Hitachi S-4800 SEM. Transmission electron microscopy (TEM) and high resolution TEM (HRTEM) images were recorded on a JEOL-2100F microscope operating at 200 kV. X-ray diffraction (XRD) experiments was carried out on a PANalytical high resolution X-ray diffraction system (model EMPYREAN) with a Cu K $\alpha$  radiation ( $\lambda = 0.15406$  nm). X-ray photoelectron spectroscopy (XPS) was recorded on a Thermo Scientific ESCALab250Xi using 200W monochromated Al K $\alpha$  radiation.

**Figure S1**



**Fig. S1.** A typical EDS spectrum of a-MoS<sub>2</sub> NA/CC.

**Figure S2**



**Fig. S2.** a) Low, b) high magnification TEM images of a-MoS<sub>2</sub> NA/CC.

Figure S3

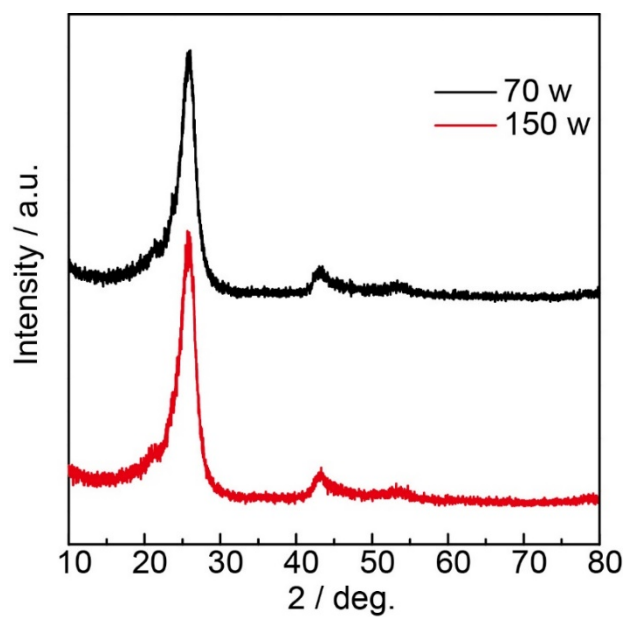


Fig. S3. XRD patterns of the as-prepared a-MoS<sub>2</sub> nanostructured thin films at different sputtering powers.

Figure S4

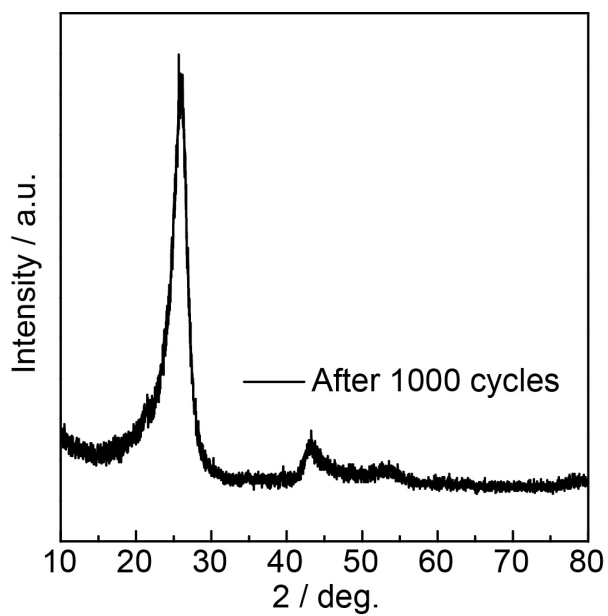
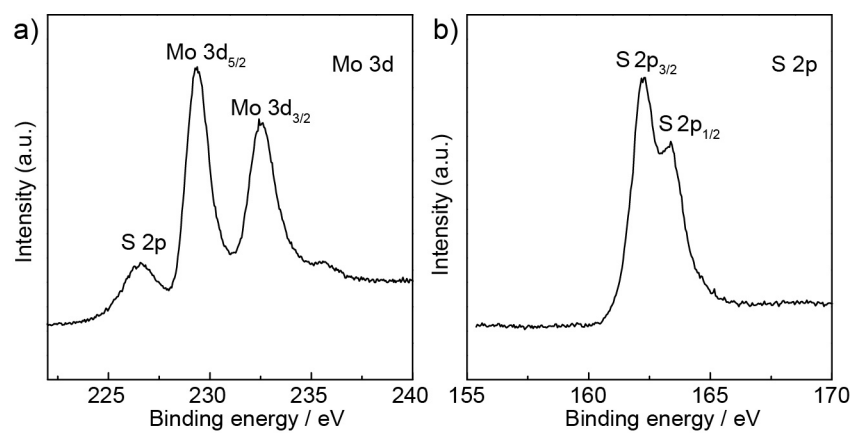


Fig. S4. XRD pattern of a-MoS<sub>2</sub> NA/CC after aging test of 1000 CV scans.

**Figure S5**



**Fig. S5.** XPS spectra of a-MoS<sub>2</sub> NA/CC after 1000 CV scans: a) high resolution Mo 3d spectrum; b) high resolution S 2p spectrum.